

FORM PTO-1449 (REV. 6-89)		U.S. DEPARTMENT OF COMMERCE Patent and Trademark Office		Attorney's Docket No. 3154	Serial No. 08/984,558
INFORMATION DISCLOSURE CITATION (Use several sheets if necessary)				Applicants David Alumot, et al.	
				Filing Date 12/03/97	Group Art Unit 2721 Unassigned

U.S. PATENT DOCUMENTS							
Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
AAJ	5 6 9 9 4 4 7	12/16/97	Alumot, et al.	382	145	RECEIVED FEB 09 1999 GROUP 2700	
AAJ	4 7 4 0 7 0 8	04/26/88	Batchelder	250	563		
AAJ	** 4 5 8 9 1 4 0	05/86	Bishop, et al.	382	8		
AAJ	** 5 1 3 3 6 0 1	07/92	Cohen, et al.	356			
AAJ	** 4 9 2 6 4 8 9	05/90	Danielson, et al.	382	8		
AAJ	4 4 4 1 1 2 4	04/03/84	Heebner, et al.	358	106		
AAJ	4 2 8 6 2 9 3	08/25/81	Jablonowski	358	199		
AAJ	5 1 5 3 6 6 8	10/06/92	Katzir, et al.	356	237		
AAJ	** 4 6 9 3 6 0 8	09/87	Kitagawa, et al.	356	394		
AAJ	** 5 1 5 9 6 4 6	10/92	Kumagai	382	34		
AAJ	** 5 2 0 4 9 1 0	04/93	Lebeau	382	8		

FOREIGN PATENT DOCUMENTS							
Document Number	Date	Country	Class	Subclass	Translation		
					<input type="checkbox"/> Yes <input type="checkbox"/> No		

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)	
AAJ	S. Kimura., K. Suda, S. Hase and C. Munakata, "Optical Method for Inspecting LSI Patterns Using Reflected Diffraction Waves", Vol. 27, No. 6, p. 1187-1192, March 15, 1986.
AAJ	J.S. Batchelder, "Pattern Wafer Scanner", IBM Technical Disclosure Bulletin, Vol. 27, No. 10B, p. 6273-6275, March, 1985.
AAJ	J.S. Batchelder, "Review of Contamination Detection on Patterned Surfaces", SPIE, Vol. 774, Lasers in Microlithography, p. 8-12, 1987.
AAJ	P.S. Grosewald, J.E. Levine. and A.C. Rapa, "Automatic Detection of Defects on Wafers", IBM Technical Disclosure Bulletin, Vol. 21, No. 6, p. 2336-2337, November, 1978.
AAJ	J.G. de la Rosa and D.M. Rose, "Wafer Inspection with a Laser Scanning Microscope", AT&T Technical Journal, p. 68-77.

EXAMINER AAJ ANDREW W. JOHNS PRIMARY EXAMINER	DATE CONSIDERED MAR 24 1999
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EXAMINER: Initial if references considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. **, No copy enclosed. Reference was cited in parent application 07/790,871.

